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*Pamela L. Patrick*

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of )  
Shunpei YAMAZAKI et al. ) Group Art Unit: 2811  
Serial No. 09/295,607 ) Examiner: S. Loke  
Filed: April 22, 1999 )  
For: SEMICONDUCTOR DEVICE HAVING )  
ALUMINUM NITRIDE FILM ) Date: December 29, 2000

**AMENDMENT**

Assistant Commissioner for Patents  
Washington, D.C. 20231

**BEST AVAILABLE COPY**

Sir:

In response to the Office Action of September 29, 2000, please amend the above-identified application as follows.

**IN THE CLAIMS:**

Please cancel claims 9, 18 and 36.

Please add new claims 43-59 as follows:

*Sub E51*  
--43. The device of claim 2 wherein said channel formation region is crystallized by laser irradiation through an insulating film.

44. The device of claim 3 wherein said channel formation region is crystallized by laser irradiation through an insulating film.

01/12/2001 LSPRUELL 00000003 192380 09295607

01 FC:102      80.00 CH  
02 FC:103      234.00 CH

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